

Abstract of the Disclosure

A micromirror actuator is provided. The micromirror actuator includes a substrate, posts formed to a predetermined height on the substrate and spaced a predetermined distance apart, a torsion bar fixed to the posts, a mirror coupled to the torsion bar, and a groove including an inclined contact surface and formed in the substrate. Here, the inclined contact surface contacts the lower bottom surface of the mirror when the mirror is rotated. The micromirror actuator can be applied to a structure in which a plurality of micromirror actuators are arrayed side-by-side and is capable of precisely and stably maintaining the rotation angle of a mirror, particularly, stably maintaining the inclination angle of the mirror irrespective of an increase in the strength of a magnetic field.

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